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XPS Submission Form – Kratos AXIS Supra+

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| **Full Name** |  |
| **Email Address** |  |
| **Phone No.** (optional) |  |
| **University of Glasgow Only** |
| **Supervisor/Research group** |  |
| **School and College** |  |
| **External Organisations Only** |
| **Organisation Name** |  |
| **Department** |  |
| **Experiment Details** |
| **Date Submitted** |  | **Number of Samples** |  |
| **Techniques Required** (note that for powder samples, only XPS can be chosen) | [ ]  XPS [ ]  UPS (conductive samples only)[ ]  XPS imaging [ ]  REELS (conductive samples only)[ ]  ARXPS [ ]  Depth Profiling (please fill in the[ ]  Surface etch with XPS relevant section on page 2) |
| **Any additional requirements** *(e.g. elements to look for, data formats)* |  |
| **Sample Details** |
| **Sample Name** | **Dimensions in mm, including thickness** | **Mass submitted** (if powder) | **Associated hazards (***please attach CoSHH form)* |
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| **Sample Description**For each sample, please provide a detailed description that must include the following:1. What physical form it is (e.g. thin film on substrate, layered device, foil, polymer, powder etc.)2. What is the structure, what components/layers/films are there and what elements are expected.3. Is the surface or substrate conductive? Is any of it strongly magnetic?4. Any other relevant details, including whether any samples are air-sensitive. |
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| **Depth Profiling / Etching Details**If you wish to include a surface etch or depth profile using the Gas Cluster Ion Source as part of your analysis, please detail your requirements in the box below.You should include:1. What are you looking for or expecting to see in a depth profile? * Are you expecting interfaces between layers/films, chemical changes, or specific elements only appearing at a certain depth? What exactly, how many changes, and to what depth?

2. Is monatomic ion etching or cluster ion etching preferable?* If you do not know, instead please note if the material is metallic, organic or inorganic, provide a detailed description of the sample
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